

## UNITED STATES PARTMENT OF COMMERCE

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United States Patent and Trademark Office

Washington, D.C. 20231

APPLICATION NO. FILING DATE FIRST NAMED INVENTOR ATTORNEY DOCKET NO. 06/01/99 09/323,230 UETANI Υ 2185-0343F **EXAMINER** 002292 IM22/0605 BIRCH STEWART KOLASCH & BIRCH CHU, J PO BOX 747 ART UNIT PAPER NUMBER FALLS CHURCH VA 22040-0747 1752

Address:

DATE MAILED:

06/05/01

Please find below and/or attached an Office communication concerning this application or proceeding.

**Commissioner of Patents and Trademarks** 

<u>.</u>	Application No.	Applicant(s)
Office Action Summary	09/323,230	UETANI ET AL.
	Examin r	Art Unit
	John S. Chu	1752
The MAILING DATE of this communication app ars on the cov r sheet with the correspondenc address Period for Reply		
A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.136 (a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.  - If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.  - Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133).  - Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).  Status		
1) Responsive to communication(s) filed on 16 April 2001.		
2a) ☐ This action is <b>FINAL</b> . 2b) ☒ This action is non-final.		
3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.		
Disposition of Claims		
4)⊠ Claim(s) <u>1 and 6-9</u> is/are pending in the application.		
4a) Of the above claim(s) is/are withdrawn from consideration.		
5) Claim(s) is/are allowed.		
6)⊠ Claim(s) <u>1 and 6-9</u> is/are rejected.		
7) Claim(s) is/are objected to.		
8) Claims are subject to restriction and/or election requirement.		
Application Papers		
9) The specification is objected to by the Examiner.		
10) The drawing(s) filed on is/are objected to by the Examiner.		
11)☐ The proposed drawing correction filed on is: a)☐ approved b)☐ disapproved.		
12) ☐ The oath or declaration is objected to by the Examiner.		
Priority under 35 U.S.C. § 119		
13)⊠ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).		
a)⊠ All b)□ Some * c)□ None of:		
1.⊠ Certified copies of the priority documents have been received.		
2. Certified copies of the priority documents have been received in Application No		
Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).  * See the attached detailed Office action for a list of the certified copies not received.		
14) Acknowledgement is made of a claim for domestic priority under 35 U.S.C. § 119(e).		
Attachment(s)		
15) Notice of References Cited (PTO-892)  16) Notice of Draftsperson's Patent Drawing Review (PTO-948)  17) Information Disclosure Statement(s) (PTO-1449) Paper No(s)	19) Notice of Informal	y (PTO-413) Paper No(s) Patent Application (PTO-152)

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## **DETAILED ACTION**

This Office action is in response to the CPA filed and preliminary amendment received

April 16, 2001.

## Claim Rejections - 35 USC § 103

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. Claims 1, 6-9 are rejected under 35 U.S.C. 103(a) as being unpatentable over the combination of TACHIKAWA ET AL and AOAI ET AL.

The claimed invention is now drawn to an article comprising a substrate comprising a silicon wafer and a positive resist composition comprising a novolac resin, a radiation-sensitive quinonediazide compound and a compound of formula (I)

TACHIKAWA ET AL discloses a photosensitive composition comprising a quinonediazide compound and a sensitizer wherein the sensitizers are disclosed in column 3, lines 3-15. Applicants are directed to line 12 for the suggestion of thioxanthone as an additive aromatic ketone.

TACHIKAWA ET AL lacks an explicit example using the claimed and disclosed thioxanthone, however it would have been *prima facie* obvious to one of ordinary skill in the art of photosensitive quinonediazide containing compositions to use any of the listed aromatic ketones with the reasonable expectation of same or similar results as disclosed in TACHIKAWA

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ET AL for the formation of positive and negative images. TACHIKAWA ET AL further lacks the explicit use of a silicon wafer as a substrate to coat the photosensitive composition.

AOAI ET AL discloses a photosensitive composition comprising a siloxane polymers, a binder resin and sensitizers wherein the siloxane is a reaction product of a siloxane polymer and a 1,2-naphthoguinone diazide compound, see column 193, lines 15-17 and column 194, lines 18-30. The composition further comprises the presence of an alkali-soluble binder such as novolaks / phenol formaldehyde resins, see column 215, line 21 - column 216, line 4.

Applicants are further directed to column 232, lines 41-65 for the disclosure of other preferred components that include sensitizers, namely a thioxanthone as seen in line 55. Further in the patent applicants disclose the use of sensitizers for the acid generators that are used in the composition as seen in column 233, lines 37-51, namely thioxanthone and 2-chlorothioxanthone. AOAI ET AL.

The composition of AOAI ET AL is further disclosed to be coated on a substrate like those recited in column 234, lines 56-68 and on silicone wafers as seen in Examples 19-26 in column 241. This disclosure meets the substrate of a silicon wafer in the recited article of claim 1.

Like TACHIKAWA ET AL, the examples fail to explicit disclose the presence of a sensitizer as claimed such as thioxanthone, however the use of sensitizers to expand the spectral range and the activate the acid generators are well known and can easily be added to provide known and expected results.

It would have been prima facie obvious to one of ordinary skill in the art of photosensitive composition to first coat either of the photosensitive compositions on a silicone

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wafer as demonstrated by the examples of AOAI ET AL. It would also been *prima facie* obvious to the skilled artisan to add known sensitizers to the photosensitive composition to expand the spectral sensitivity of the compositions as well as help activate the acid generators as taught by AOAI ET AL.

Motivation is based on the desire to expand the spectral sensitivity of the composition as well as activate the acid generators.

The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. WINKLE is cited of interest, which discloses the use of sensitizers to extend the sensitivity of the photoresist film.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to John S. Chu whose telephone number is (703) 308-2298. The examiner can normally be reached on M-F from 9:30 am to 6:00 pm.

The fax phone number for the organization where this application or proceeding is assigned is (703) 305-3599.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 308-0661.

John S. Chu

Primary Examiner, Group 1700

J.Chu June 3, 2001